INFORMATION DISCLOSURE STATEMENT  
PTO Form 1449Pocket Number  
00900.0302-US-C1Serial Number  
10/675886Applicant(s)  
Christian Petersen, et al.Filing Date  
September 30,  
2003Group Art Unit  
2856-2829

## U.S. PATENT DOCUMENTS

EXAMINER INITIALS	REF	DOCUMENT NUMBER	DATE	NAME	CLASS	SUB-CLASS	FILING DATE (IF APPROPRIATE)
<i>RL</i>	—	4,520,314	05/28/85	Asch, et al.	—	—	—
<i>RL</i>	—	5,171,992	12/15/92	Clabes, et al.	—	—	—
<i>RL</i>	—	5,347,226	09/13/94	Bachmann, et al.	—	—	—
<i>RL</i>	—	5,475,318	12/12/95	Marcus, et al.	—	—	—
<i>RL</i>	—	5,540,958	07/30/96	Bothra, et al.	—	—	—
<i>RL</i>	—	5,557,214	09/17/96	Barnett	—	—	—
<i>RL</i>	—	5,613,861	03/25/97	Smith, et al.	—	—	—

## FOREIGN PATENT DOCUMENTS

EXAMINER INITIALS	REF	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUB-CLASS	TRANSLATION	
							YES	NO
		EP 0 299 875	01/18/89	European Patent Office				
		01147374	06/09/89	Japan			Abstract	
		EP 0 466 274	01/15/92	European Patent Office				
		DE 43 01 420	06/24/93	Germany				
		WO 94/11745	05/26/94	WIPO				
		07199219	08/04/95	Japan			Abstract	
		0-15310	01/19/96	Japan				
		DE 196 48 475	06/05/97	Germany				
		EP 0 899 538	03/03/99	European Patent Office				


## OTHER DOCUMENTS

		Fujii, et al., "Micropattern measurement with an atomic force microscope", <u>Journal of Vacuum Science &amp; Technology: Part B</u> , Vol. 9, No. 2, pp. 666-669 (March/April 1991).
		Hong, et al., "Design and Fabrication of a Monolithic High Density Probe Card for High-Frequency On-Water Testing", <u>Institute of Electrical and Electronics Engineers</u> , pp. 289-292 (December 3, 1999).
		Koops, et al., "Constructive three dimensional lithography with electron beam induced deposition for quantum effect devices", <u>Journal of Vacuum Science &amp; Technology B (Microelectronics Processing and Phenomena)</u> , Vol. 11, No. 6, pp. 2286-2289 (November/December 1993).
		Koops, et al., "Conductive dots, wires, and supertips for field electron emitters produced by electron-beam induced deposition on samples having increased temperature", <u>Journal of Vacuum Science &amp; Technology B (Microelectronics Processing and Phenomena)</u> , Vol. 14, No. 6, pp. 4105-4109 (November/December 1996).
		International Search Report for PCT/DK99/00301
		Lee, et al., "High Density Silicon Microprobe Arrays for LCD Pixel Inspection", <u>Institute of Electrical and Electronics Engineers</u> , pp. 429-434 (February 11, 1996).
		Niu, et al., "Double tip scanning tunneling microscope for surface analysis", <u>Physical Review B</u> , Vol. 51, No. 8, pp. 5502-5505 (February 15, 1995).
		Shi, et al., "New method of calculating the correction factors for the measurement of sheet resistivity of a square sample with a square four point probe", <u>Rev. Sci. Instrum.</u> , Vol. 68, No. 4, pp. 1814-1817 (April 1997).

Examiner: 

Date Considered: 11-20-05

<b>INFORMATION DISCLOSURE STATEMENT</b> PTO Form 1449		<b>Docket Number</b> 00900.0302-US-C1	<b>Serial Number</b> 10/675886
		<b>Applicant(s)</b> Christian Petersen, et al.	
		<b>Filing Date</b> September 30, 2003	<b>Group Art Unit</b> <del>2858</del> 2829
		<del>Smits, "Measurement of Sheet Resistivities with the Four Point Probe", The Bell System Technical Journal, Vol. 37, pp. 711-718 (May 1958).</del>	

<b>Examiner:</b> 	<b>Date Considered:</b> 11-20-05
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